

IN THE CLAIMS

1 (Previously Presented). A method comprising:
forming a pore in an insulator;
forming a heater in said pore by filling said pore with a conductive material and
then removing the upper portion of said conductive material;
filling the upper portion with a phase change material that extends over said
insulator;
forming a substantially planar upper surface of said phase change material; and
forming a substantially planar upper electrode over said substantially planar upper
surface of said phase change material.

Claims 2 and 3 (Canceled).

4 (Previously Presented). The method of claim 1 including planarizing the upper
surface of said insulator.

Claims 5 and 6 (Canceled).

7 (Previously Presented). The method of claim 1 including patterning and etching
said phase change material over said insulator.

8 (Original). The method of claim 7 including forming a T-shaped phase change
material.

9 (Currently Amended). The method of claim 3 1 including forming a sidewall
spacer in said pore.

10 (Currently Amended). The method of claim 9 wherein forming a heater includes
~~including~~ depositing metal in said pore after forming said sidewall spacer.

Claims 11-31 (Canceled).